



REPLY UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER ART UNIT 1763

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
HONGOH, T.

Application No.: 09/536,721

Confirmation No. 5386

Filed: March 28, 2000

Group: 1763

Title: MICROWAVE PLASMA PROCESSING APPARATUS FOR
CONTROLLING A TEMPERATURE OF A WAVELENGTH
REDUCING MEMBER

Examiner: CROWELL, A.

* * * *

October 17, 2003

REQUEST FOR RECONSIDERATION

Hon. Commissioner of Patents
Washington, DC 20231

Sir:

RECEIVED
OCT 21 2003
TC 1700

Responsive to the Office Action dated September 5, 2003, reconsideration and allowance of the present application based on the following remarks are respectfully requested.